

Fig. 1A formation of base insulating film/ formation of semiconductor film

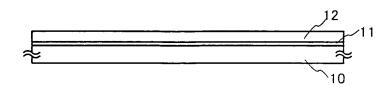


Fig. 1B laser anneal

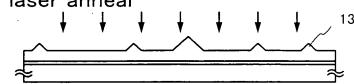


Fig. 1C heat treatment process

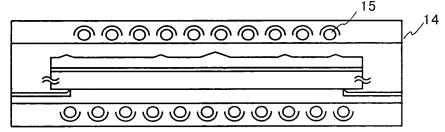
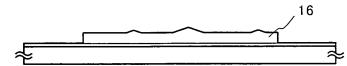


Fig. 1D formation of semiconductor film



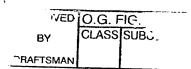


Fig. 2A formation of base insulating film/ formation of semiconductor film

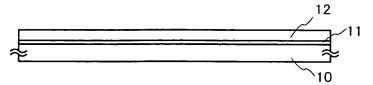


Fig. 2B laser anneal

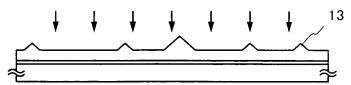


Fig. 2C formation of semiconductor film

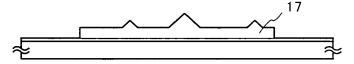


Fig. 2D heat treatment process

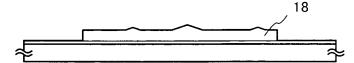


Fig. 3A formation of base insulating film/ formation of semiconductor film

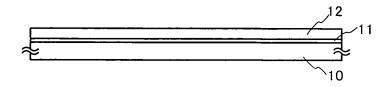


Fig. 3B irradiation of strong light

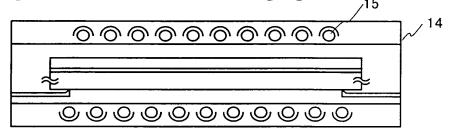


Fig. 3C laser anneal

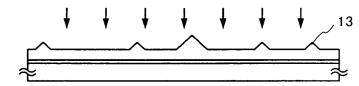


Fig. 3D heat treatment process

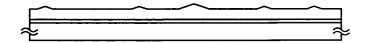
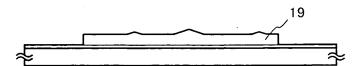


Fig. 3E formation of semiconductor film



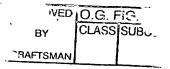


Fig. 4A formation of conductive film/formation of insulating film /formation of semiconductor film

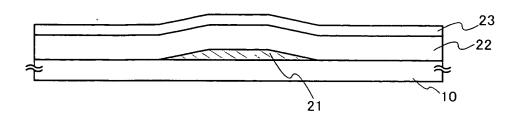


Fig. 4B laser anneal

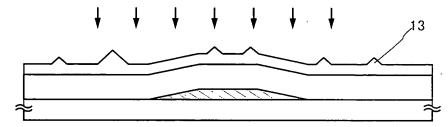


Fig. 4C heat treatment process

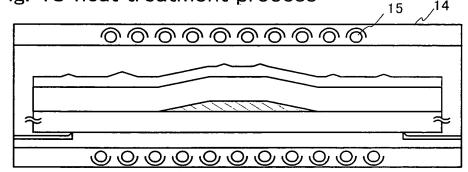
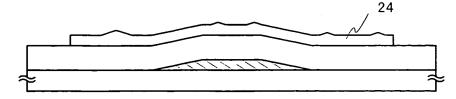
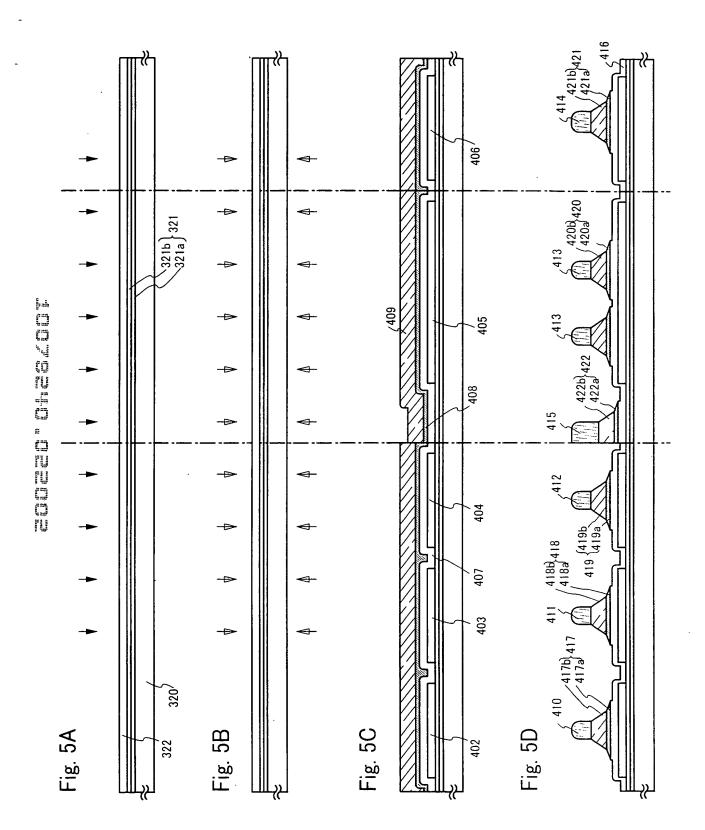
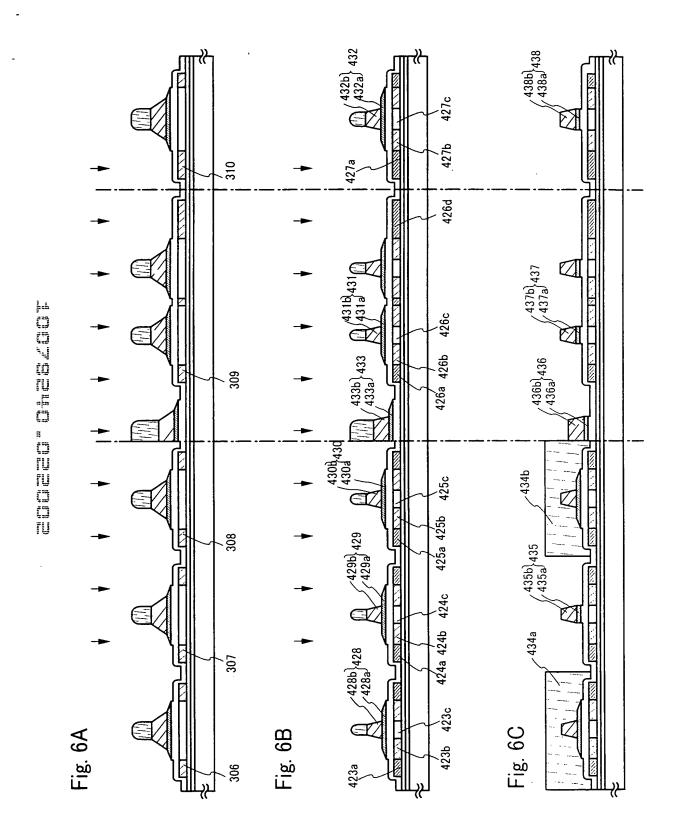


Fig. 4D formation of semiconductor film







446a 446b 446c 446d Fig. 7C Fig. 7A Fig. 7B

Fig. 8

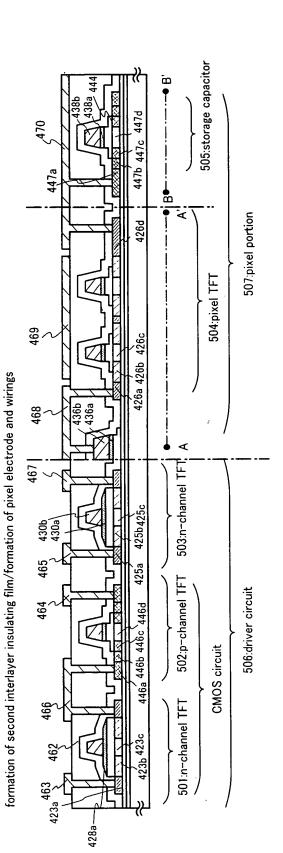
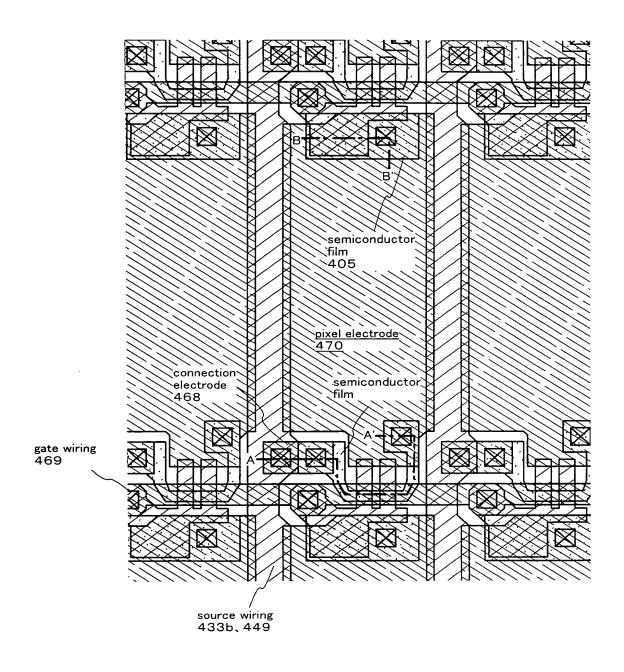


Fig. 9



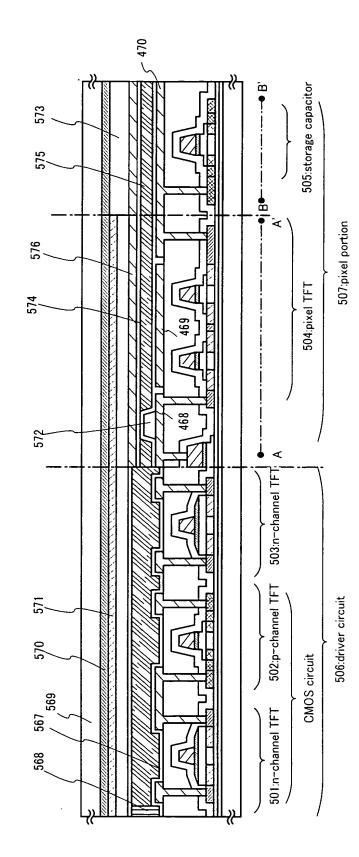


Fig. 11

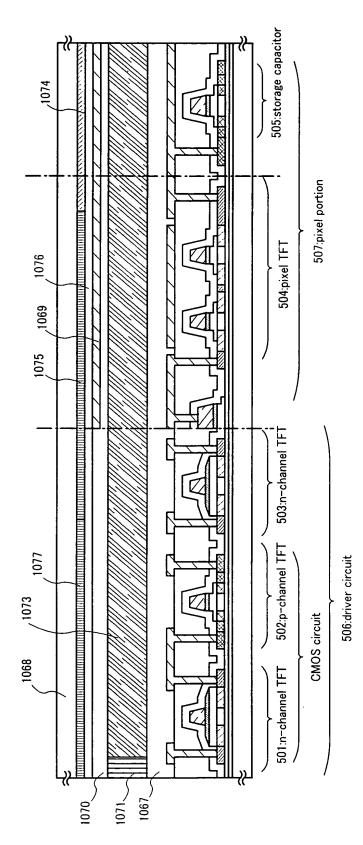
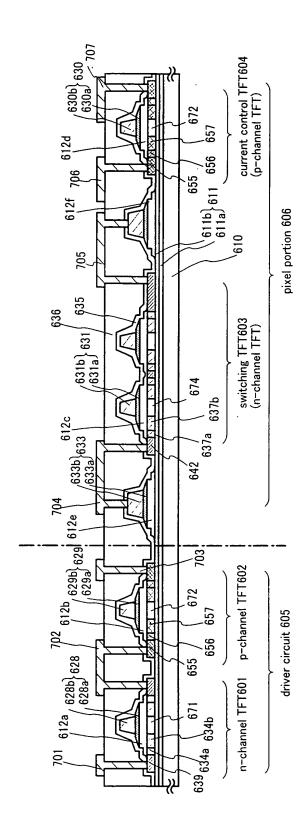
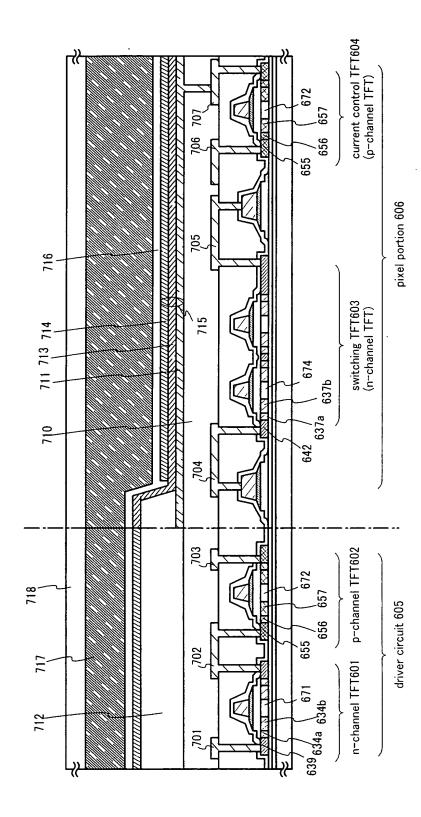
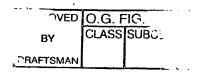
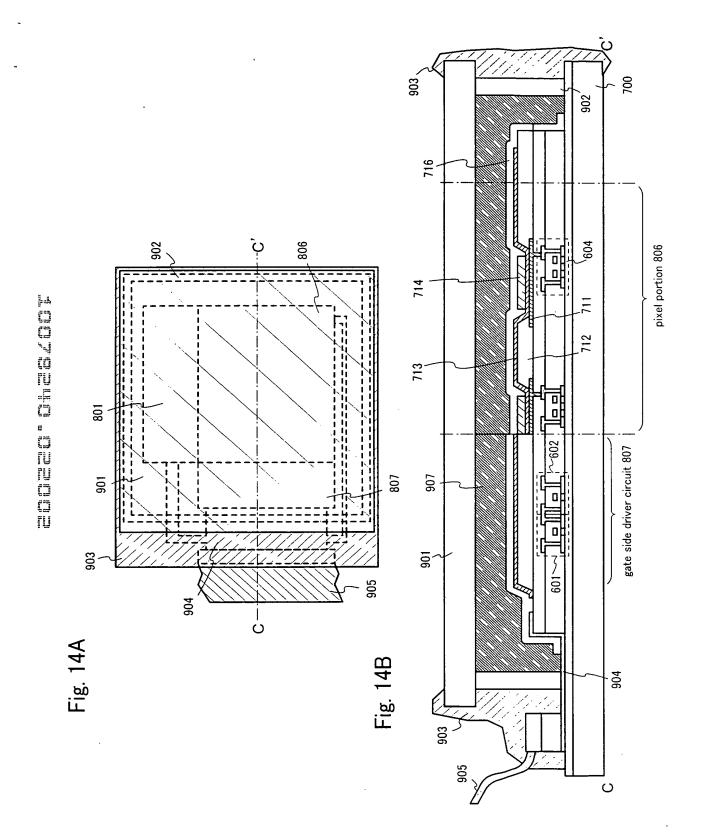


Fig. 12









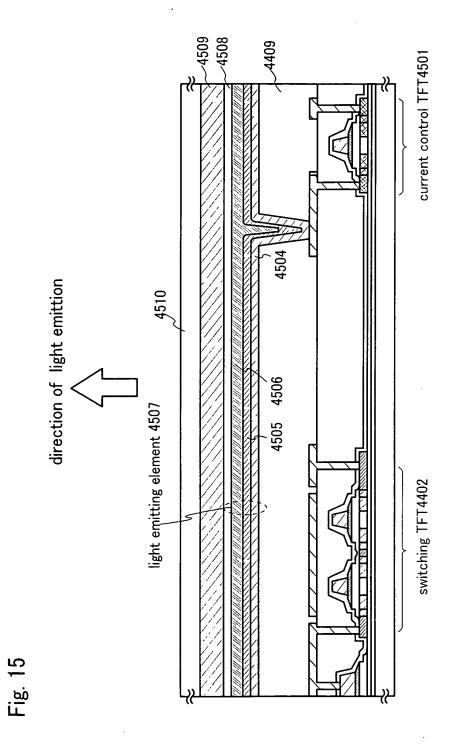


Fig. 16A

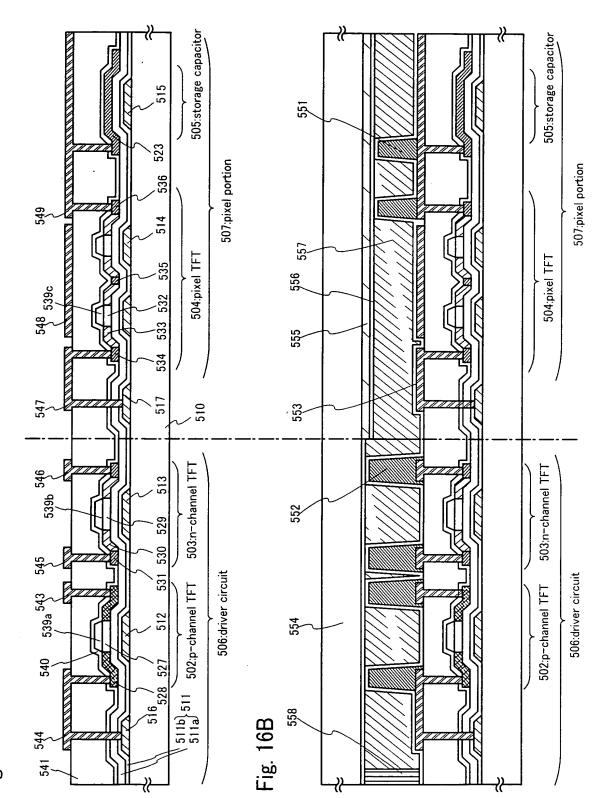
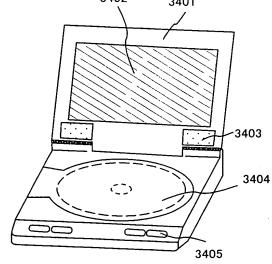


Fig. 17

4509 current control TFT4501 4504 4510 direction of light emittion 4506 4505 light emitting element 4507 switching TFT4402

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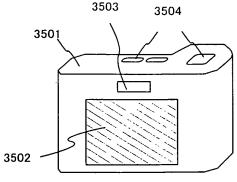
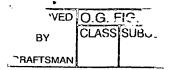


Fig. 18E

Fig. 18F



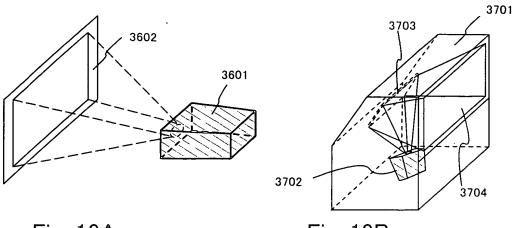


Fig. 19A

Fig. 19B

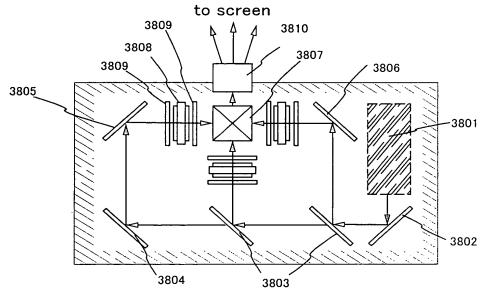


Fig. 19C

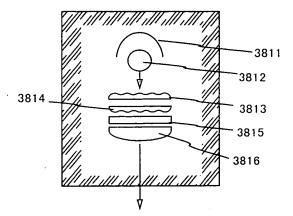


Fig. 19D



